## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No.	:	09/546,174		Confirmation No.:	4793
Applicant	:	Chih-Chien Liu			
Filing Date	:	April 11, 2000			
Title	:	HIGH DENSITY PROCESS	PLASMA CHE	EMICAL VAPOR DEPO	OSITION
Group Art L	Jnit :	1796			
Examiner	:	Sergent, Rabon	A.		
Docket No.	:	20952.4002			
Customer N	lo. :	34313			
Commission Mail Stop A P.O. Box 14 Alexandria,	F 150			RESPONSE UNDE 1.116 EXPEDITED P EXAMINING G 4793	ROCEDURE
Transmitted				FINAL REJECTION	n the
above-ident	ified app		to the Notice o	of Appeal on June 13, 2	
☐ If an there		al extension of time	is required, pl	ease consider this a pe	etition
Attac	hed is a	General Power Atto	rney.		
Attac	hed is St	tatement Under 37 (	CFR 3.73(b).		
There is no	fee requ	ired:			
Fee Calculat A.		credit any overpayme Charge any additiona Deposit Account No.	nts to Deposit I fee required u	zed to charge indicated f Account No. <u>15-0665</u> nder 37 CFR 1.16 and 1.	
B.		Payment Enclosed Check	Credit Card	Money Order	] Other

 Applicant
 Chih-Chien Liu

 Appl. No.
 09/546,174

 Examiner
 Sergent, Rabon A.

 Docket No.
 20952,4002

Total Claims	40	-	49	=	0	×	\$50.00	0
Independent Claims	3	-	3	=	0	х	\$210.00	0
Multiple Dependent Claims	\$370	(if a	pplica	ible)				
TOTAL OF ABOVE CALCULA	TIONS							
Reduction by 1/2 for Filing by Sm	all Entity. N	lote 37	CFR	§§ 1	.9, 1.2	7, 1.	28.	
				••				
Extension of Time (from above)	•							0
	:) 🗆							0

Respectfully submitted,

ORRICK, HERRINGTON & SUTCLIFFE LLP

Dated: 8-12-08

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